

Al Thermal Diffusion in Ge and $\text{Si}_x\text{Ge}_{1-x}$ Nanowires: A Novel Approach towards 1D Heterostructure Fabrication

Luong Minh Anh^a, Robin Eric^a, Pauc Nicolas^b, Gentile Pascal^b, Baron Thierry^c, Salem Bassem^c, Sistani Masiar^d, Lugstein Alois^d, Spies Maria^e, Fernandez Bruno^e, den Hertog Martien^e

- a. Université Grenoble Alpes, CEA, IRIG-DEPHY, F-38054 Grenoble, France
- b. Université Grenoble Alpes, CEA, IRIG-DEPHY, PHELIQS/SINAPS, F-38000 Grenoble, France
- c. Université Grenoble Alpes, CNRS, LTM, 38054 Grenoble, France
- d. Technische Universität Wien, Institute of Solid State Electronics, Gußhausstraße 25, Vienna 1040, Austria
- e. Université Grenoble Alpes, CNRS, Institut NEEL UPR2940, 25 Avenue des Martyrs, Grenoble 38042, France

* email : minhanhpc@gmail.com, martien.den-hertog@neel.cnrs.fr

Thermally activated solid state reactions forming metal silicides (germanides) nanowire heterostructures have recently received special interests as they could be either employed as a platform to study the Fermi-level pinning effect at metal- Si (Ge) junctions or used as building blocks for fabricating short-channel devices such as photodetectors, single-electron transistors by Coulomb blockade effect or state-of-the-art field effect transistors (FETs). We study the Al-Ge binary system, combining ex-situ and in-situ heating methods, and present a proof of principle experiment carried out in-situ in a transmission electron microscope where we precisely control the metal propagation speed and produce an axial Al/Ge/Al nanowire heterostructure with an ultra-short Ge segment down to 7 nanometers [1]. In the Al- (Ge, Si) ternary system, the thermal reaction results in the creation of a Si-rich region sandwiched between the reacted Al and unreacted $\text{Si}_x\text{Ge}_{1-x}$ part, forming an axial Al/Si/ $\text{Si}_x\text{Ge}_{1-x}$ heterostructure. Upon heating or (slow) cooling, the Al metal can repeatedly move in and out of the $\text{Si}_x\text{Ge}_{1-x}$ alloy nanowire while maintaining the rod-like geometry and crystallinity, see Fig. 1, allowing to fabricate and contact nanowire heterostructures in a reversible way in a single process step, compatible with current Si based technology [2].

- (1) M. A. Luong, *ACS Appl. Nano Mater.* **2020**, 3 (2), 1891–1899.
- (2) M. A. Luong, *ACS Appl. Nano Mater.* **2020**, 3 (10), 10427–10436.

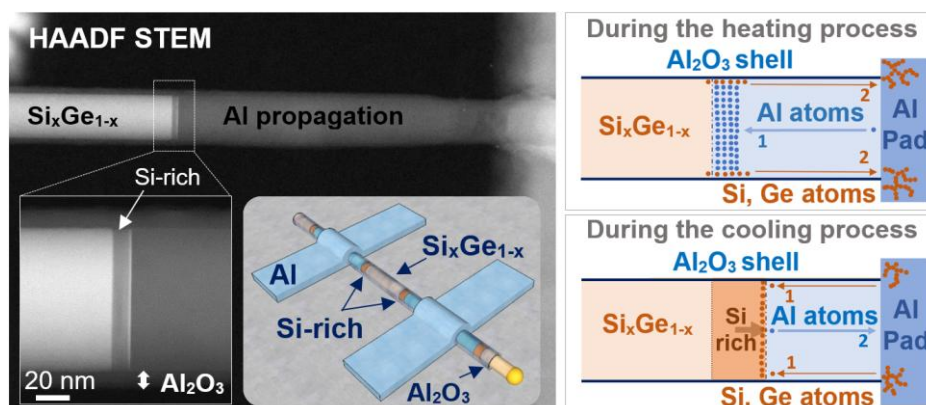


Figure 1: HAADF - STEM images of Al thermal propagation in passivated $\text{Si}_x\text{Ge}_{1-x}$ NW (with 20 nm Al_2O_3 shell) showing the formation of Al/Si-rich/ $\text{Si}_x\text{Ge}_{1-x}$ heterostructure, and schematic illustrations of the diffusion paths of Si, Ge and Al atoms during the heating and cooling process, respectively.